



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Zheng, et al.

Serial No.: 09/614,407

Confirmation No.: 1903

Filed: July 12, 2000

For: Method of Application of
Electrical Biasing to Enhance
Metal Deposition

Group Art Unit: 1741

Examiner: Smith-Hicks, E.

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Box RCE
Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

CERTIFICATE UNDER 37 CFR 1.10	
I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on <u>10-15</u> , 2002 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. <u>EV0155454088US</u> addressed to: Box RCE, Commissioner for Patents, Washington, D.C. 20231.	
Date <u>10/15/02</u>	Signature <u>Asi Krametz</u>

PRELIMINARY AMENDMENT

Applicants, in accordance with 37 C.F.R. §1.114(c), request consideration of the following amendments prior to the examination of the attached Request for Continued Prosecution of the above identified application.

IN THE CLAIMS:

Please add the following new claims:

Sub C1
85. (New) A method of depositing a metal on a substrate having one or more features formed thereon, comprising:

applying a first biasing voltage to the substrate while immersing the substrate into an electrolyte solution contained in an electrolyte container comprising an anode immersed in the electrolyte solution, wherein the first biasing voltage increases over time; and

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